PATENT 450101-04870.1

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants:

Koichiro KISHIMA et al.

Serial No.:

10/540,720

International Application No.:

PCT/JP04/16188

International Filing Date:

October 25, 2004

For:

METHOD FOR MANUFACTURING SEMICONDUCTOR SUBSTRATE AND

SEMICONDUCTOR SUBSTRATE

Confirmation No.:

2419

745 Fifth Avenue New York, NY 10151

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Mail Stop Box PCT, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on January 9, 2006.

Thomas F. Presson, Reg. No. 41,442
Name of Applicant, Assignee or Registered Representative

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January 9, 2006

Date of Signature

COMMUNICATION

Mail Stop Box PCT Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

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Sir:

Enclosed herewith is a copy of the "Notification of Missing Requirements" (form

PCT/DO/EO/905) dated December 23, 2005 on the above application, a Declaration duly signed

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by the inventor and a check in the amount of the required \$130.00 surcharge. By separate cover, we are filing the Assignment and the \$40.00 fee for recording same.

Please charge any additional fees incurred or credit any overpayment to Deposit Account No. 50-0320.

In view of the foregoing, it is believed that the identified application is now complete. Early examination of the application on its merits is solicited.

Respectfully submitted,

FROMMER LAWRENCE & HAUG LLP Attorneys for Applicants

01/16/2006 RTRANI 00000152 10540720

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130.00 DP

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